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# A “Click” Reaction to Engineer MoS<sub>2</sub> Field-Effect Transistors with Low Contact Resistance

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**KEY WORDS:** Two-dimensional materials, covalent functionalization, carrier doping, contact resistance, thermal stability

**Abstract:** Two-dimensional (2D) materials with the atomically thin thickness have attracted great interest in the post-Moore's Law era because of their tremendous potential to continue transistor downscaling and offered advances in device performance at the atomic limit. However, the metal-semiconductor contact is the bottleneck in field-effect transistors (FETs) integrating 2D semiconductors as channel materials. A robust and tunable doping method at the source and drain region of 2D transistors to minimize the contact resistance is highly sought after. Here we report a stable carrier doping method via the mild covalent grafting of maleimides on the surface of 2D transition metal dichalcogenides. The chemisorbed interaction contributes to the efficient carrier doping without degrading the high-performance carrier transport. Density functional theory results further illustrate that the molecular functionalization leads to the mild hybridization and the negligible impact on the conduction bands of monolayer MoS<sub>2</sub>, avoiding the random scattering from the dopants. Differently from reported molecular treatments, our strategy displays high thermal stability (above 300 °C) and it is compatible with micro/nano processing technology. The contact

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resistance of MoS<sub>2</sub> FETs can be greatly reduced by ~12 times after molecular functionalization. The Schottky barrier of 44 meV is achieved on monolayer MoS<sub>2</sub> FETs, demonstrating efficient charge injection between metal and 2D semiconductor. The mild covalent functionalization of molecules on 2D semiconductors represents a powerful strategy to perform the carrier doping and the device optimization.

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Two-dimensional (2D) materials maintain a high carrier mobility down to the sub-1 nm thickness and show high immunity to the short-channel effect, displaying the potential to ultimately scale down the transistor dimensions.<sup>1-3</sup> However, the charge transport in field-effect transistors (FETs) based on 2D semiconductor channels has been hampered by extrinsic factors, such as the high contact resistance, interface scattering and defects.<sup>1-3</sup> In the meanwhile, a strong Fermi level pinning effect is observed between bulk metals and 2D semiconductors, making the realization of Ohmic contact challenging.<sup>4</sup> It is the prerequisite to achieve the efficient injection of charge carrier from the contacts to the 2D semiconductor channel to achieve the high-performance operation, especially in short-channel and high-frequency transistors.

In traditional silicon-based technology, degenerate doping by ion implantation can effectively minimize the contact resistance and reduce the Schottky barrier to enhance the carrier injection. Although the ion implantation is not compatible with ultrathin 2D materials due to the severe formation of defects, the degenerate doping at the contact region is an effective methodology to perform contact engineering in 2D FETs. Chhowalla *et al.* reported the use of phase-engineered metallic MoS<sub>2</sub> as the contact to achieve an ultralow contact resistance of 200-300  $\Omega \cdot \mu\text{m}$  at zero gate bias.<sup>4</sup> Recently, semimetallic bismuth was used to form high-quality Ohmic contact with monolayer MoS<sub>2</sub> due to the suppression of the metal-induced gap states and the degenerate doping at the contact region.<sup>5</sup> Molecular functionalization of 2D FETs with decanethiol,<sup>6</sup> benzyl viologen,<sup>7,8</sup> NO<sub>2</sub>,<sup>9</sup> and tungsten oxyselenide<sup>10</sup> at the contact regions have been successfully demonstrated to improve the charge injection. However, the thermal

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stability is the bottleneck of these methods and the molecular functionalization methods also exhibit the poor complementary metal-oxide-semiconductor (CMOS) compatibility. The covalent functionalization of a 2D semiconductor channel with molecules show the advantages of the high thermal stability, but degrade the electrical transport properties because the highly ordered crystalline structure of 2D semiconductors would be interrupted by the molecules. It is highly desirable to develop a mild covalent functionalization method to simultaneously achieve the stable carrier doping of 2D semiconductors, preserve the excellent electrical transport properties of 2D layers, display high thermal stability, and be compatible with CMOS process.

In this work, we propose a powerful strategy to realize efficient n-type doping on 2D transition metal disulfide MoS<sub>2</sub> via a mild “click” reaction. The sulfur atoms with soft nucleophilicity react with maleimide via Michael addition to achieve the covalent functionalization.<sup>11</sup> The molecular functionalization at the channel region results in the increased electron density of MoS<sub>2</sub> by  $2.18 \times 10^{12} \text{ cm}^{-2}$ . The material and device characterizations demonstrate the successful n-type doping of the MoS<sub>2</sub> layer. The functionalized MoS<sub>2</sub> layers are compatible with micro/nano fabrication process and the fabricated transistors show high thermal stability at over 300 °C. Furthermore, by using a micropatterning process, the contact regions between metal and MoS<sub>2</sub> are selectively doped via the mild “click” reaction. The average contact resistance of MoS<sub>2</sub> transistors is as low as 4.4 kΩ·μm, which is 12 times smaller than pristine devices. The Schottky barrier has been reduced to 44 meV in monolayer MoS<sub>2</sub> transistors with Au electrodes. The field-effect mobility of monolayer and three-layer MoS<sub>2</sub> FETs reaches values as

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high as 57 and 61  $\text{cm}^2\text{V}^{-1}\text{s}^{-1}$ , respectively. Density functional theory results indicate that electron transport of  $\text{MoS}_2$  is dominated by the  $d$  orbitals of Mo atoms, which have not been interfered by the C-S bonds of molecular functionalization. The mild covalent functionalization provides a feasible pathway to optimize the performance of 2D transistors, which is compatible with back-end-of-line (BEOL) integration in large-scale production.

## Results and discussion

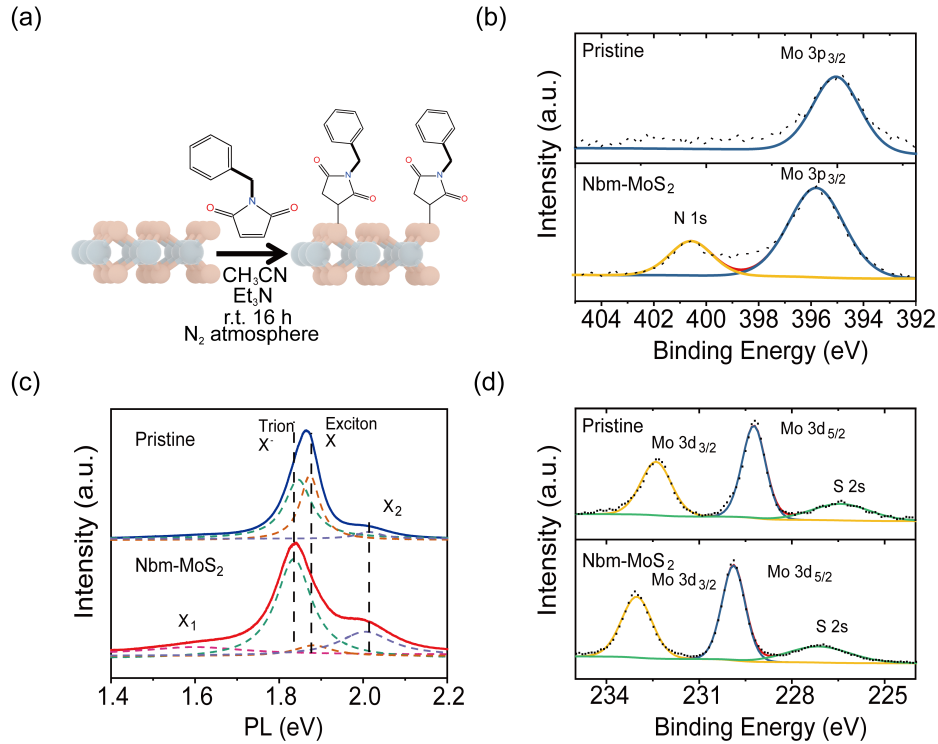
Thiol-maleimide “click” reaction via Michael addition is an efficient approach to achieve surface modification in polymers and biomaterials. In 2019, Pérez *et al.* demonstrated the successful covalent functionalization of liquid-phase exfoliated transition metal disulfides (TMDs) with maleimide via a “click” reaction,<sup>11</sup> showing the potential to perform covalent functionalization of 2D semiconductors under mild conditions. The  $\text{MoS}_2$  flakes in our work were mechanically exfoliated from bulk  $\text{MoS}_2$  crystals and transferred to the  $\text{SiO}_2/\text{Si}$  substrate (oxide thickness 285 nm). Figure 1a schematically illustrates the covalent functionalization process and the experimental details can be found in the Method section. Generally, the  $\text{MoS}_2$  samples were soaked overnight in the solution comprised of *N*-benzylmaleimide, acetonitrile, and triethylamine at room temperature under a  $\text{N}_2$  atmosphere. X-ray photoelectron spectroscopy (XPS) was employed to characterize the covalent C-N bonding in  $\text{MoS}_2$  after the functionalization with *N*-benzylmaleimide (abbreviated as Nbm- $\text{MoS}_2$ ). Compared with pristine  $\text{MoS}_2$ , a characteristic peak for N 1s appears as shown in Figure

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1b, which can be unambiguously assigned to the maleimide fragment. After 350 °C annealing, N 1s peak is greatly weakened (Figure S1) due to the desorption of covalently attached materials, which is consistent with the thermogravimetric analysis of the Nbm-MoS<sub>2</sub> samples as reported by Pérez *et al.*<sup>11</sup>

Raman spectra of Nbm-MoS<sub>2</sub> and pristine MoS<sub>2</sub> display typical A<sub>1g</sub> and E<sub>2g</sub><sup>1</sup> Raman peaks in Figure S2a. The crystal structure of MoS<sub>2</sub> has been well preserved. Photoluminescence (PL) spectroscopy is a reliable method to characterize the doping of layered TMDs.<sup>12</sup> Figure 1c shows the PL spectra of Nbm-MoS<sub>2</sub> and pristine MoS<sub>2</sub> with A and B exciton peaks. The A exciton peak of monolayer MoS<sub>2</sub> consists of a neutral exciton peak (E(X) ≈ 1.88 eV) and a negatively charged trion peak (E(X<sup>-</sup>) ≈ 1.84 eV),<sup>13</sup> and the spectra weight is an indicator of the MoS<sub>2</sub> electron density.<sup>14</sup> Our results show that the weight of the neutral exciton peak decreased from 41.7 % to 6.3 %, and the trion peak weight increased from 52.7 % to 59.8 %, demonstrating the increase of electron density in MoS<sub>2</sub>. The emergence of a new peak (X<sub>1</sub>) at 1.60 eV in Nbm-MoS<sub>2</sub> demonstrates the existence of mid-gap states and the hybridization between MoS<sub>2</sub> and *N*-benzylmaleimide. The XPS spectra of Mo and S core levels for pristine and Nbm-MoS<sub>2</sub> are shown in Figure 1d and S2b. The Mo 3d peaks and S 2p peaks show blue shift after Nbm functionalization, demonstrating the electron doping. The material characterization results prove the efficient n-type doping of MoS<sub>2</sub> after molecular functionalization.





**Figure 1.** Spectroscopic characterizations of the functionalized MoS<sub>2</sub> (Nbm-MoS<sub>2</sub>). (a) Schematic of the mild “click” reaction between MoS<sub>2</sub> and N-benzylmaleimide. (b) XPS spectra of N 1s core level for pristine MoS<sub>2</sub> and Nbm-MoS<sub>2</sub>. (c) Photoluminescence (PL) spectra of the pristine MoS<sub>2</sub> and Nbm-MoS<sub>2</sub>. (d) XPS spectra of Mo core level for pristine MoS<sub>2</sub> and Nbm-MoS<sub>2</sub>.

The preservation of excellent electrical transport properties of the functionalized MoS<sub>2</sub> samples is crucial to their applications in advanced electronic devices. To investigate the electrical properties of Nbm-MoS<sub>2</sub> FETs, the back-gate top-contact MoS<sub>2</sub> FETs were fabricated on hexagonal boron nitride (h-BN)/SiO<sub>2</sub> bilayer dielectric substrate with 40-nm-thick Au top electrodes, and then the exposed MoS<sub>2</sub> channel was functionalized with *N*-benzylmaleimide (Figure 2a). The device fabrication details are

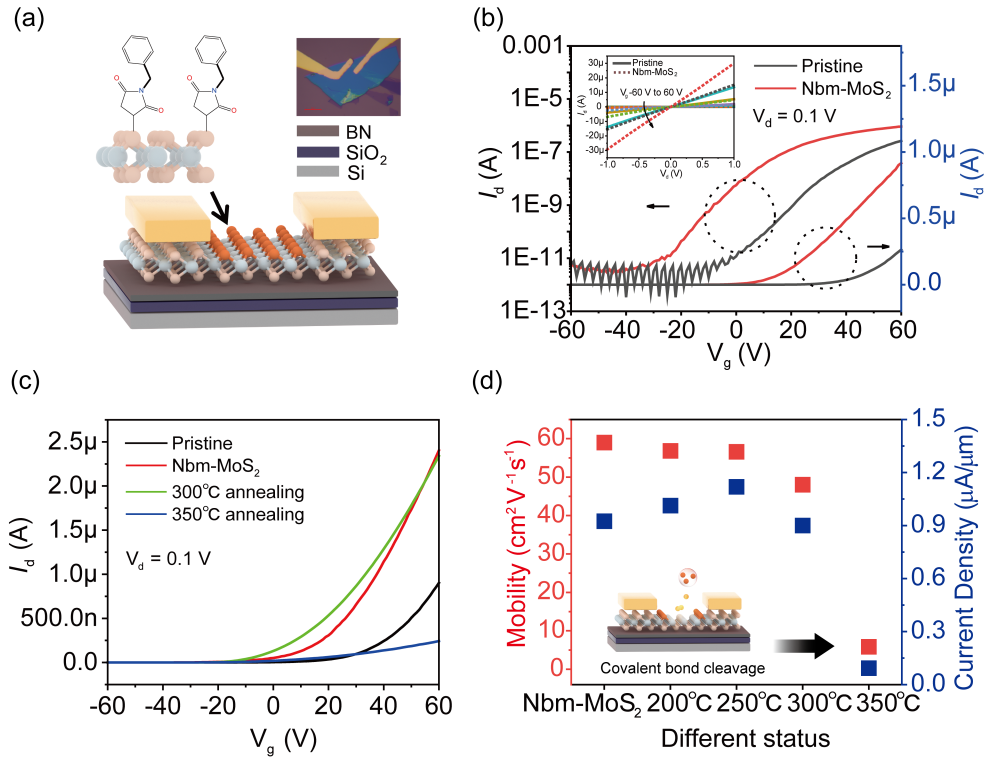
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provided in the Method section. The h-BN is used as an interfacial dielectric layer to improve the quality of the MoS<sub>2</sub>/dielectric interface because the carriers in the atomically thin MoS<sub>2</sub> can be dramatically scattered by the defects and surface states of SiO<sub>2</sub>.<sup>15, 16</sup> Figure 2b shows the transfer and output characteristics of the monolayer MoS<sub>2</sub> FETs before and after the molecular functionalization (0.5 mmol *N*-benzylmaleimide) in the channel region. Compared with pristine MoS<sub>2</sub> FETs, the Nbm-MoS<sub>2</sub> FETs exhibit improved on-state current, comparable off-state current, increased I<sub>on</sub>/I<sub>off</sub> ratio (over 10<sup>5</sup>), and the negative shift of the threshold voltage ( $\Delta V_{th} = 29$  V). It suggests that *N*-benzylmaleimide can induce the n-doping in MoS<sub>2</sub> which is evidenced by an electron density change ( $\Delta n$ ) of  $2.18 \times 10^{12}$  cm<sup>-2</sup>. Taking advantage of the mild covalent functionalization, the field-effect mobility increases from 33 cm<sup>2</sup>V<sup>-1</sup>s<sup>-1</sup> (pristine) to 59 cm<sup>2</sup>V<sup>-1</sup>s<sup>-1</sup> (Nbm-MoS<sub>2</sub>). The increased electron density of monolayer MoS<sub>2</sub> greatly screen the scattering and improve the carrier mobility. The hysteresis of transfer curves of Nbm-MoS<sub>2</sub> FET can reflect the MoS<sub>2</sub>/molecule interface quality. Compared with pristine device, the Nbm-MoS<sub>2</sub> FET (0.1 mmol Nbm) displays a small hysteresis as shown in Figure S3a, demonstrating the limited influence of functionalized molecules on the electron transport of MoS<sub>2</sub> FETs. The concentration of *N*-benzylmaleimide determines the functional ratio and the charge density in MoS<sub>2</sub>. We further explored the relation between the functionalization ratio and the charge transport in Nbm-MoS<sub>2</sub> FETs as shown in Figure S4 and obtained the optimized molecular concentration. In devices fabricated on SiO<sub>2</sub>/Si substrate, the monolayer Nbm-MoS<sub>2</sub>

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FETs show weak electrostatic gate modulation and high off-state current (Figure S5), demonstrating the degenerate doping of MoS<sub>2</sub> by *N*-benzylmaleimide molecules.

One important merit of the covalent functionalization is the high thermal stability, which is also a significant prerequisite for large-scale production and BEOL integration. In experiment, the Nbm-MoS<sub>2</sub> FETs were annealed at several temperatures from 200 °C to 350 °C to show the thermal stability. The thermal annealing was performed in a tube furnace at low pressure with 100 sccm H<sub>2</sub>/Ar (10%/90%) flow. After the annealing treatment at 200 °C, 250 °C, and 300°C, the device preserved the excellent electrical transport behavior (Figure 2c, 2d and Figure S6), further demonstrating the formation of covalent bonds between MoS<sub>2</sub> and *N*-benzylmaleimide, instead of physisorption (boiling point of *N*-benzylmaleimide is 177 °C). After 350 °C annealing, the electrical transport performance dramatically degraded due to the desorption of covalently attached materials and the figures of merit of Nbm-MoS<sub>2</sub> FETs were even worse than the performance before thermal annealing. The disappearance of N 1s peak in the XPS spectra of Nbm-MoS<sub>2</sub> after 350 °C annealing (Figure S1) provides evidence for the desorption of Nbm fragments. The thermal stability tests show that the mild covalent bonding of *N*-benzylmaleimide on monolayer MoS<sub>2</sub> surface can simultaneously improve the electrical transport properties and display high thermal stability. In comparison, conventional doping strategies by physisorbed molecules mostly show poor thermal stability and cannot endure a high-temperature process.<sup>17</sup> Therefore, our method exhibits a valuable advantage in large-scale production and BEOL integration.



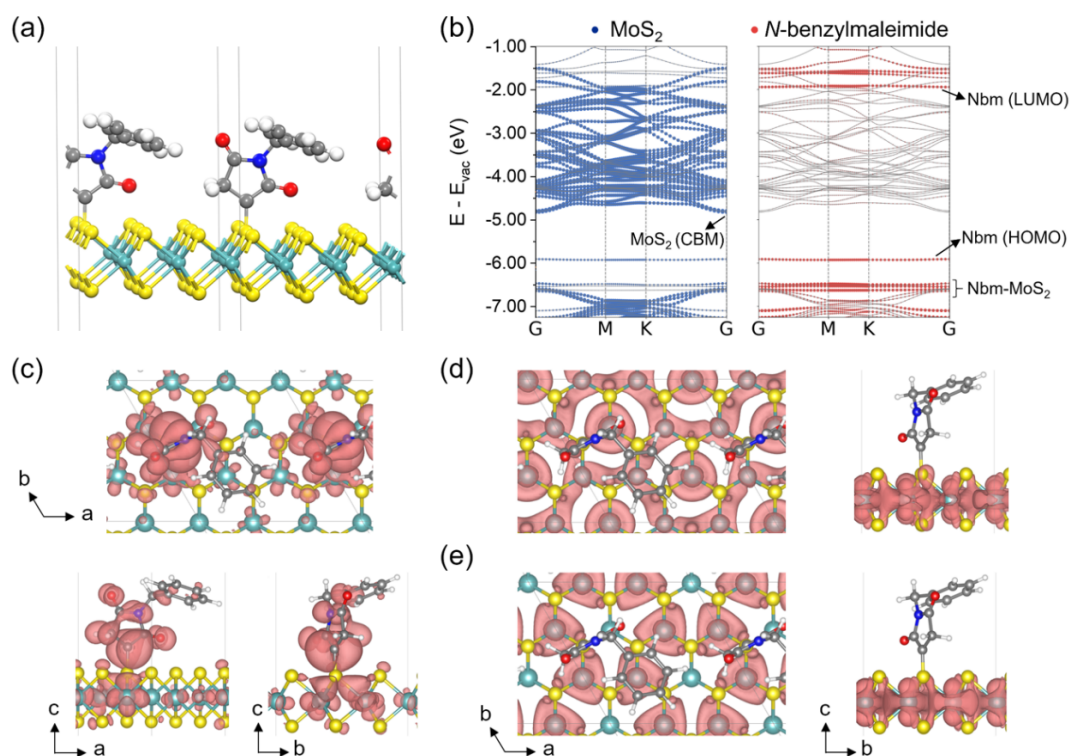
**Figure 2.** Electrical characterizations of monolayer Nbm-MoS<sub>2</sub> FETs. (a) Schematic of the Nbm-MoS<sub>2</sub> FET with the channel region functionalized with *N*-benzylmaleimide. (b) Transfer curves of the pristine and Nbm-MoS<sub>2</sub> FET. Inset shows the output curves. (c) Transfer curves of the pristine MoS<sub>2</sub> FET, Nbm-MoS<sub>2</sub> FET, and Nbm-MoS<sub>2</sub> FETs after 300 °C and 350 °C annealing, respectively. (d) Mobility and current density are extracted from Figure 2c and Figure S6. The dramatic performance degradation after 350 °C annealing indicates the cleavage of covalent bonds.

In pristine samples, the sulfur atom in MoS<sub>2</sub> is covalently bound to three Mo atoms. The “click” reaction with maleimide induces the formation of hypervalent S species with covalent bonds to three Mo atoms and one C atom. Finally, the negative formal charge on the S atoms would facilitate the electron extraction and hence the electronic properties of TMDs can be efficiently modulated via the covalent functionalization. To

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explore the in-depth mechanism of the excellent electrical transport of Nbm-MoS<sub>2</sub>, we further performed first-principles DFT calculations to study the electronic structure of Nbm-MoS<sub>2</sub>. The most energetically favored structure of Nbm-MoS<sub>2</sub> is shown in Figure 3a (see Figure S7 for more discussions). The chemical absorption manifests as covalent C-S bonding and the hydrogen atom is transferred to the adjacent C atoms. To explore the influence of the covalent functionalization of MoS<sub>2</sub> with *N*-benzylmaleimide, we calculated the decomposed atomic/orbital band structure of Nbm-MoS<sub>2</sub> (Figure 3b). A mid-gap state, identified as the highest occupied molecule orbital (HOMO) of the *N*-benzylmaleimide, emerged in the bandgap of pristine MoS<sub>2</sub>. The norm of the wavefunctions for the localized mid-gap state, Nbm-HOMO labeled in Figure 3b, were visualized in Figure 3c. As shown in Figure S8, the states around valence bands maximum (VB1 and VB2) of pristine MoS<sub>2</sub> are contributed by *p* orbital of S atoms. In comparison, the six valence bands below the band of Nbm-HOMO in Nbm-MoS<sub>2</sub> present C-S bonding (Figure S9), which has a negative effect on the hole transport of MoS<sub>2</sub>. However, the conduction band minimum states of MoS<sub>2</sub> are mainly comprised of Mo *dz*<sup>2</sup> orbital (CB1 of Figure S8b) and the electron transport of MoS<sub>2</sub> has not been interfered with the covalently functionalized molecules on MoS<sub>2</sub> (Figure 3d and 3e). Actually, as the projected bands on the orbital of Nbm molecule shown in the red dots of Figure 3b, the lowest unoccupied orbital (LUMO) of the *N*-benzylmaleimide arises at ~3 eV higher than the conduction band minimum (CBM) band of Nbm-MoS<sub>2</sub>, which have negligible influence on the electron transport of MoS<sub>2</sub>. Overall, the mild covalent functionalization of MoS<sub>2</sub> with *N*-benzylmaleimide can increase the electron density,

preserve the intrinsic electron transport properties without any degradation, and suppress the impurity scattering from external environment. These results demonstrate the mild covalent functionalization is a powerful strategy to engineer the properties of MoS<sub>2</sub> and optimize the device performance.



**Figure 3.** Geometric and Electronic band structure of Nbm-MoS<sub>2</sub>. (a) Atomic configuration of Nbm-MoS<sub>2</sub>. (b) Decomposed atomic band structure of Nbm-MoS<sub>2</sub>. Blue and red dots represent the bands decomposed on the orbitals of MoS<sub>2</sub> (left panel) and the N-benzylmaleimide molecules (right panel), respectively. The highest occupied molecular orbital (HOMO) and the lowest unoccupied molecular orbital (LUMO) of the N-benzylmaleimide, the highest valence bands and the conduction band minimum (CBM) of MoS<sub>2</sub> are labeled as Nbm (HOMO), Nbm (LUMO), Nbm-MoS<sub>2</sub> and MoS<sub>2</sub>-(CBM), respectively. (c) Spatial structure of wavefunction norms for the Nbm-HOMO

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states labelled in b at the G point in the *ab*, *ac* and *bc* planes, respectively. (d-e) Spatial structure of wavefunction norms for the two-fold degenerated MoS<sub>2</sub>-CBM states at the G point. Isosurface level of (c)-(e) is  $1.0 \times 10^{-4} e/\text{Bohr}^3$ .

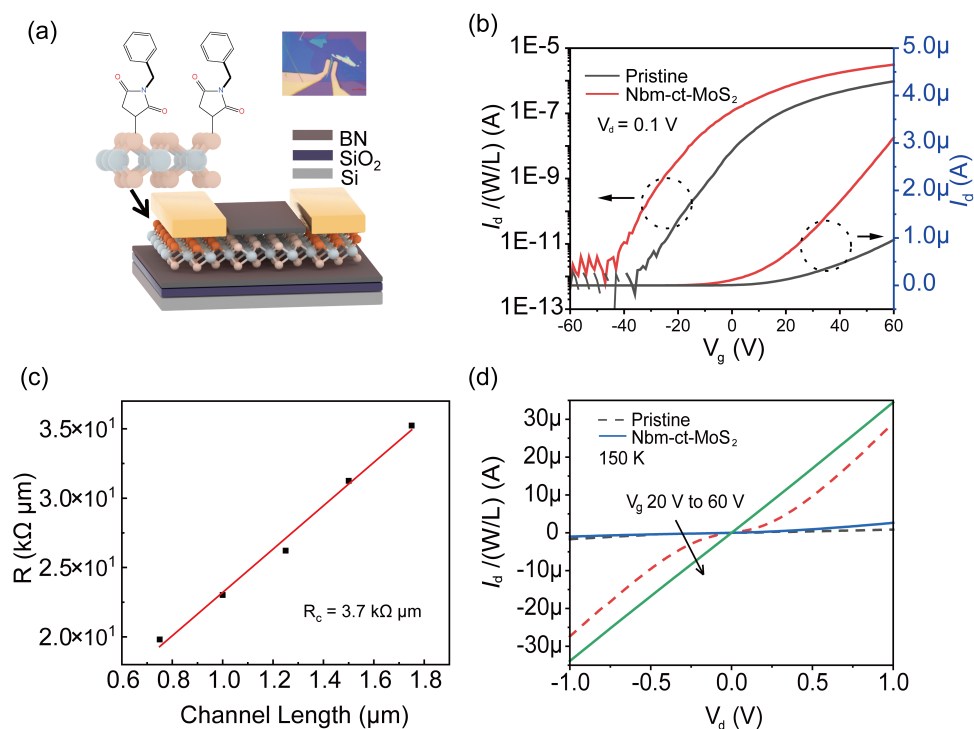
As the covalent functionalization method can effectively modulate the electronic properties and even realize degenerate doping of MoS<sub>2</sub>, it is interesting to apply this strategy to decrease the contact resistance of MoS<sub>2</sub> FETs. In MoS<sub>2</sub> transistors, the existence of Schottky barriers at the metal-semiconductor interface fundamentally leads to high contact resistance, which follows the Mott-Schottky rule.<sup>18</sup> The degenerate doping of 2D semiconductors at the contact region will effectively decrease the Schottky barrier and reduce the contact resistance. The schematic of the device structure with contact engineering is shown in Figure 4a and the MoS<sub>2</sub> transistors were selectively doped at the contact region by the *N*-benzylmaleimide molecules (abbreviated as Nbm-ct-MoS<sub>2</sub> FETs). To investigate the carrier injection at the semiconductor/metal junction in Nbm-ct-MoS<sub>2</sub> FETs, the transfer and output curves at different temperatures were measured in a cryogenic probe station. For the sake of comparison, the drain current is normalized by channel length and width. The transfer curves of monolayer MoS<sub>2</sub> FET are shown in Figure 4b. Owing to the improved charge injection at the semiconductor/metal junction, the electrical transport performance of monolayer Nbm-ct-MoS<sub>2</sub> FET has been significantly enhanced. The field-effect mobility of monolayer MoS<sub>2</sub> FETs was increased from  $20 \text{ cm}^2\text{V}^{-1}\text{s}^{-1}$  to  $57 \text{ cm}^2\text{V}^{-1}\text{s}^{-1}$  at room temperature and the normalized drain current was boosted from  $0.9 \mu\text{A}$  to  $3.1 \mu\text{A}$

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at  $V_d = 0.1$  V. The pristine MoS<sub>2</sub> and Nbm-ct-MoS<sub>2</sub> FETs were fabricated on the same flake to avoid device variation (Figure S10) and the Nbm-ct-MoS<sub>2</sub> FET displayed improved performance, undoubtedly proving the positive effect of Nbm. We further employed the transfer length method (TLM) to characterize the contact resistance.<sup>19</sup> Figure 4c plots the normalized resistance as a function of the channel length and the contact resistance is extracted from the y-intercept of the fitted linear line. With the molecular doping at the contact region, the device of three-layer Nbm-ct-MoS<sub>2</sub> FET reaches a contact resistance ( $R_c$ ) as low as  $3.7 \text{ k}\Omega\cdot\mu\text{m}$ . Raman and AFM characterizations in Figure S11 confirm the uniformity and the thickness of the channel layer. Compared with the average contact resistance of pristine MoS<sub>2</sub> FET of  $52.9 \text{ k}\Omega\cdot\mu\text{m}$  (Figure S12), the average contact resistance of Nbm-ct-MoS<sub>2</sub> FETs of  $4.4 \text{ k}\Omega\cdot\mu\text{m}$  (Figure S13) is greatly reduced by 12 times. The output curves of the Nbm-ct-MoS<sub>2</sub> FET and pristine MoS<sub>2</sub> FET at 150 K are displayed in Figure 4d. The excellent Ohmic contact in the Nbm-ct-MoS<sub>2</sub> FET contributes to the linear output curves even at low temperature, while the pristine MoS<sub>2</sub> FET with Schottky contact shows nonlinear output curves. Owing to the high-quality contact and dielectric interface in Nbm-ct-MoS<sub>2</sub> FET, the hysteresis is nearly zero on monolayer Nbm-ct-MoS<sub>2</sub> FETs as shown in Figure S3b. A Nbm-ct-MoS<sub>2</sub> FET with a 500 nm channel length was fabricated and the device displayed a high current density of  $83.4 \mu\text{A}/\mu\text{m}$  at  $V_d = 1\text{V}$  as shown in Figure S14. These results demonstrate that the molecular functionalization at the contact region effectively reduces the contact resistance and improves the charge injection between 2D materials and the metal contact. We would like to point out that this high-



quality molecular functionalization strategy is compatible with the micro/nano fabrication process, because the functionalization procedure is carried out before the patterning and the deposition of source/drain electrodes.



**Figure 4.** Contact engineering of MoS<sub>2</sub> FETs by covalent functionalization. (a) Schematic of the MoS<sub>2</sub> FET with *N*-benzylmaleimide functionalized at the contact region (Nbm-ct-MoS<sub>2</sub> FET). (b) Transfer curves of monolayer Nbm-ct-MoS<sub>2</sub> FET and pristine MoS<sub>2</sub> FET. (c) The normalized resistance of three-layer Nbm-ct-MoS<sub>2</sub> FETs at V<sub>g</sub> = 60 V along with the channel lengths. Contact resistance has been extracted from the fitted linear line by the transfer length method (TLM). (d) Output curves of the Nbm-ct-MoS<sub>2</sub> FET and pristine MoS<sub>2</sub> FET at 150 K.

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Systematic temperature-dependent electrical transport characterizations are performed on pristine MoS<sub>2</sub> FETs and Nbm-ct-MoS<sub>2</sub> FETs. In pristine monolayer MoS<sub>2</sub> FET (Figure 5a), the drain current shows a dramatic drop with the decreasing temperature, owing to the reduction of thermionic emission current at contact. Due to the two-probe measurement configuration, the MoS<sub>2</sub>/metal contact greatly affects the temperature-dependent charge transport. Monolayer and three-layer Nbm-ct-MoS<sub>2</sub> FETs in Figure 5b and 5c only exhibit a slight decrease of the drain current when temperature reduces from 300 K to 150 K. In the meanwhile, a carrier-density dependent metal-insulator transition (MIT) has been observed in Nbm-ct-MoS<sub>2</sub> FETs,<sup>20</sup> indicating the formation of good MoS<sub>2</sub>/metal contact to achieve the efficient charge injection even at low temperature.

The temperature-dependent field-effect mobilities of the pristine monolayer, monolayer Nbm-ct-MoS<sub>2</sub>, and three-layer Nbm-ct-MoS<sub>2</sub> FETs have been plotted in Figure 5d. Within the temperature range from 300 K to 200 K, phonon scattering is the dominant mechanism to affect the electron mobility of MoS<sub>2</sub> and the mobility is expected to follow a  $\mu \sim T^{-\gamma}$  temperature dependence. The value of  $\gamma$  in pristine monolayer MoS<sub>2</sub> FETs is nearly zero, which proves that the contact resistance is dominant factor rather than phonon scattering. In monolayer and three-layer Nbm-ct-MoS<sub>2</sub> FETs, the value of  $\gamma$  is 0.73 and 1.02, respectively. These numbers are approaching the theoretically predicted value for monolayer (1.52) and bulk (2.6) MoS<sub>2</sub> on the SiO<sub>2</sub>/Si substrate.<sup>21, 22</sup> Previous works have demonstrated that both the top and the bottom dielectric environment can induce phonon screening or a change in the strength of electron-

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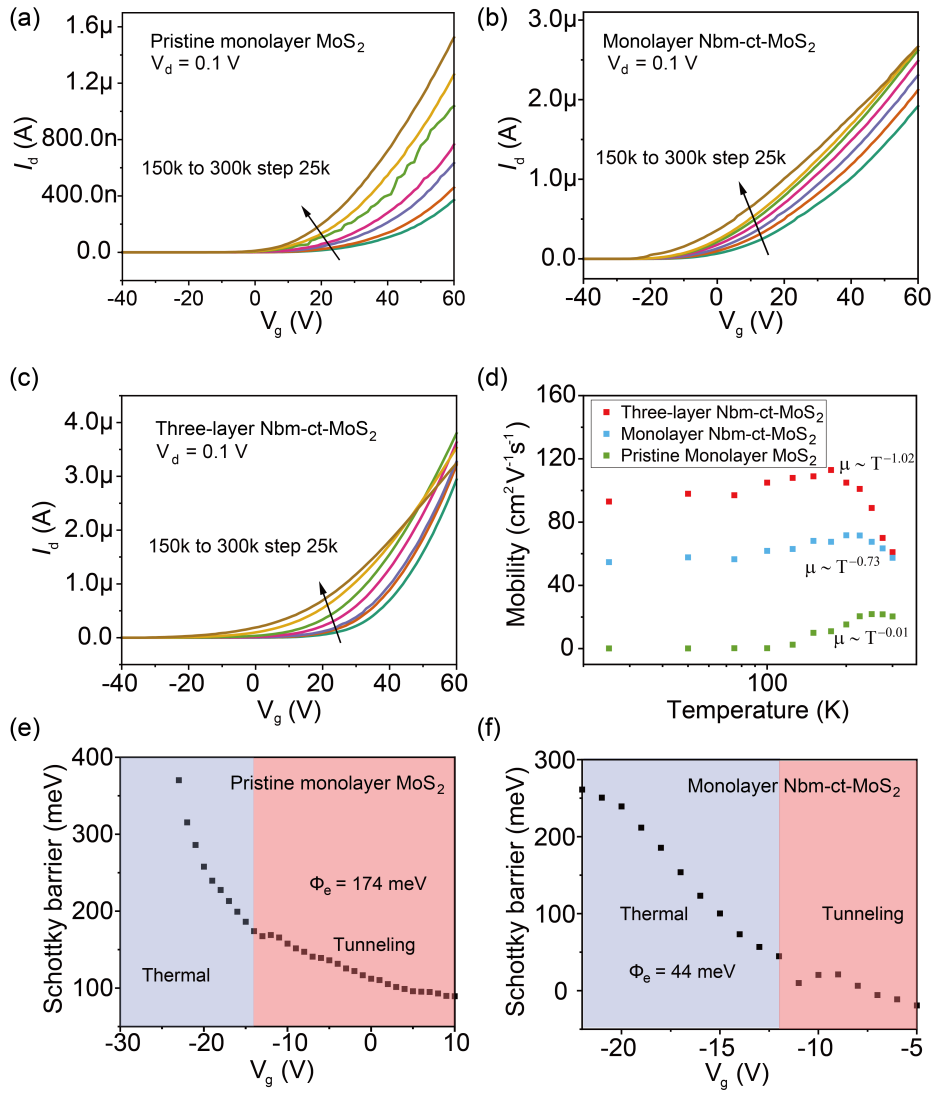
phonon coupling, resulting in the decrease of the  $\gamma$  value.<sup>23</sup> Therefore, the slightly small  $\gamma$  value in Nbm-ct-MoS<sub>2</sub> FETs is perhaps due to the encapsulation of the MoS<sub>2</sub> channel by top and bottom h-BN layers. At low temperature below 200 K, the field-effect mobility of pristine monolayer MoS<sub>2</sub> FET greatly drops, and the mobility below 100 K becomes even smaller than 1 cm<sup>2</sup>V<sup>-1</sup>s<sup>-1</sup> because of the very limited charge injection from the MoS<sub>2</sub>/metal contact. In contrast, monolayer and three-layer Nbm-ct-MoS<sub>2</sub> FETs maintain the high electron mobility until 25 K owing to the good MoS<sub>2</sub>/metal contact and the weak impurity scattering.

The Schottky barrier can be extracted from the temperature-dependent electrical transport results. The drain current in the subthreshold region mainly depends on the thermionic emission current and the thermally-assisted tunneling current. When the gate voltage ( $V_g$ ) is below the flat-band voltage ( $V_{FB}$ ), the thermionic emission current dominates the current. When  $V_g$  is larger than  $V_{FB}$ , thermally-assisted tunneling current becomes dominant. When  $V_g$  equals  $V_{FB}$ , the Schottky barrier ( $\Phi_B$ ) can be extracted.<sup>24-</sup>

<sup>26</sup> The Schottky barrier heights of pristine monolayer MoS<sub>2</sub> FET and monolayer Nbm-ct-MoS<sub>2</sub> FET are 174 meV and 44 meV (Figure 5e and 5f), respectively. The average Schottky barrier heights of pristine MoS<sub>2</sub> and Nbm-ct-MoS<sub>2</sub> FETs are shown in Figure S15 and S16, which is consistent with our representative devices. This confirms that the molecular functionalization at the contact region in Nbm-ct-MoS<sub>2</sub> FET can effectively modulate the work function of MoS<sub>2</sub> and reduce the Schottky barrier of MoS<sub>2</sub> FETs.

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Several mechanisms contribute to the improved metal/MoS<sub>2</sub> contact in Nbm-ct-MoS<sub>2</sub> FETs. The functionalized molecule with the height of ~1 nm on MoS<sub>2</sub> surface can act as the tunneling layer between metal and MoS<sub>2</sub> to suppress the Fermi level pinning effect.<sup>27, 28</sup> The tunneling layer can be clearly seen in the cross-sectional high-resolution transmission electron microscopy (HR-TEM) image (Figure S17). The molecules can slightly increase the distance between metal and semiconductor and decouple the orbital overlap. The interfacial layer can also prevent the damage of MoS<sub>2</sub> surface from the high-energy metal atoms during the metal deposition process. Moreover, the theoretical band alignment between the CBM of Nbm-MoS<sub>2</sub> and the work function of Au shows the reduced Schottky barrier (Figure S18). Therefore, the increased electron density of Nbm-MoS<sub>2</sub> reduces the contact resistance and the Schottky barrier, facilitating the electron injection.



**Figure 5.** Temperature-dependent electrical characterizations of Nbm-ct-MoS<sub>2</sub> FETs.

Temperature-dependent transfer curves of (a) pristine monolayer MoS<sub>2</sub> FETs, (b) monolayer Nbm-ct-MoS<sub>2</sub> FETs, and (c) three-layer Nbm-ct-MoS<sub>2</sub> FETs. (d) Temperature-dependent electron mobilities of pristine monolayer MoS<sub>2</sub> FETs, monolayer Nbm-ct-MoS<sub>2</sub> FETs, and three-layer Nbm-ct-MoS<sub>2</sub> FETs. Extraction of Schottky barriers from (e) pristine monolayer MoS<sub>2</sub> FETs and (f) monolayer Nbm-ct-MoS<sub>2</sub> FETs.

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## Conclusion

In conclusion, we dramatically reduced the contact resistance of MoS<sub>2</sub> FETs via the efficient n-type doping of MoS<sub>2</sub> at the contact region, realized by a mild covalent functionalization of MoS<sub>2</sub> with *N*-benzylmaleimide. This method can dope MoS<sub>2</sub> without interrupting the electron transport of MoS<sub>2</sub>. Different from the traditional molecular doping methods, this strategy exhibits excellent thermal stability (above 300 °C), preserves the high-performance carrier transport behavior, and is compatible with micro/nano fabrication technology. The Nbm-ct-MoS<sub>2</sub> FET reached low contact resistance of 4.4 kΩ·μm by performing the selective doping at the contact region. The mild “click” reaction represents a versatile strategy to modulate the electronic properties of 2D semiconductors and optimize the electrical transport performance of 2D FETs.

## Methods

**Materials.** Bulk molybdenum disulfide (MoS<sub>2</sub>) crystals were purchased from Sixcarbon Technology. The Hexagonal Boron Nitride (h-BN) was purchased from HQ Graphene. The acetonitrile (ACN) was purchased from Sigma-Aldrich. The *N*-benzylmaleimide and triethylamine (Et<sub>3</sub>N) were purchased by TCI. The commercial polydimethylsiloxane film (PDMS) was purchased from Shanghai Onway Technology Co., Ltd. The silicon wafers were purchased from Suzhou Research Materials Microtech Co., Ltd.

**Device fabrication and characterization.** h-BN flakes and MoS<sub>2</sub> flakes were mechanically exfoliated by the Scotch-tape method, transferred to PDMS, and then

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transferred on the oxidized silicon substrate ( $t_{\text{ox}} = 285 \text{ nm}$ ). The thickness of flakes was monitored by an optical microscope and confirmed by Raman spectroscopy and Atomic Force Microscopy (AFM). MoS<sub>2</sub> FETs were fabricated by direct-write lithography and Au electrodes (40nm) by thermal evaporation. The lift-off process was carried out in acetone. The as-fabricated devices were annealed for 30 minutes in a mixture of hydrogen (5%) and argon (95%) to improve the devices' performance. The *N*-benzylmaleimide and triethylamine were added to the ACN. The MoS<sub>2</sub> FETs reacted in the mixture overnight at the glovebox. All the devices were electrically characterized in a Lake shore probe station connected to a Keithley 4200. The Raman and PL spectra of MoS<sub>2</sub> were acquired with a Renishaw InVia spectrometer equipped with a 532nm laser.

**The Calculation of Carrier Density.** The pristine carrier density in 2D materials  $n_{2D}$  can be calculated based on the following equation:

$$n_{2D} = \frac{\sigma_{2D}}{q\mu} = \frac{I_d L}{V_d W q \mu}$$

where the  $\sigma_{2D}$  is the conductivity of the 2D materials,  $q$  is the elementary charge,  $L$  and  $W$  are the channel length and width, and  $\mu$  is carrier mobility. Therefore, the functionalization with *N*-benzylmaleimide (Nbm) induced charge density could be extracted by  $\Delta n = C_i \frac{\Delta V_{th}}{q}$ , where the  $\Delta V_{th}$  is the variation induced by Nbm,  $C_i$  is the capacitance of dielectric per unit area.

**The Calculation of Carrier Mobility.** The carrier mobility  $\mu$  was determined by  $\mu =$

$$\frac{dI_d}{dV_g} \times \frac{L}{WC_i V_d}.$$

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**The Calculation of Schottky barriers.** We extracted the Schottky barriers by using the thermionic emission equation  $I_d = AA_{2D}^* T^{\frac{3}{2}} \exp \left[ -\frac{q}{k_B T} \left( \Phi_B - \frac{V_d}{n} \right) \right]$ , where  $A$  is contact area of junction,  $A_{2D}^*$  is the two-dimensional equivalent Richardson constant,  $q$  is the magnitude of the electron charge,  $\Phi_B$  is the Schottky barrier height,  $k_B$  is the Boltzmann constant,  $n$  is the ideality factor, and  $V_d$  is the drain-source bias.<sup>24,26</sup>

The Arrhenius plot ( $\ln (I_d/T^{3/2})$  vs  $1000/T$  curves for various  $V_g$ ) was plotted and the slope ( $S$ ) is subsequently plotted as a function of  $V_g$ . In this way, the  $\Phi_B$  under various gate voltages and the effective  $\Phi_B$  (under the flat-band condition) can be obtained.

**Theoretical calculations.** Density functional theory (DFT) calculations were performed using the generalized gradient approximation for the exchange-correlation potential, the projector augmented wave method<sup>29</sup> and a plane-wave basis set as implemented in the Vienna ab-initio simulation package (VASP)<sup>30</sup>. Dispersion correction was made at the van der Waals density functional (vdW-DF)<sup>31, 32</sup> level, with the optB86b functional for the exchange potential (optB86b-vdW)<sup>32, 33</sup>, which was proved to be accurate in describing the structural properties of layered materials<sup>34, 35</sup>. A  $3 \times 3$  supercell of MoS<sub>2</sub> and a vacuum layer of around 16 Å were adopted in calculations. The kinetic energy cut-off for the plane-wave basis was set to 500 eV. A  $7 \times 7 \times 1$   $k$ -mesh and a Gaussian smearing with sigma of 0.01 eV were used for geometric properties optimization and electronic structure calculations. In structural relaxations, all atoms were fully relaxed until the residual force on every atom was less than 0.02 eV/Å.



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## ASSOCIATED CONTENT

### Supporting Information

The Supporting Information is available free of charge on the ACS Publications website at DOI: xxxxx.

Figure S1-S6, S10 and S12-S17: Materials and electrical characterization of MoS<sub>2</sub> FETs (pristine and Nbm-MoS<sub>2</sub>) dependent on the concentrations of *N*-benzylmaleimide, the annealing temperature, and the selected substrates. Figure S7-S9 and S18: Atomic configurations of Nbm-MoS<sub>2</sub> considered in DFT calculations, electronic structures of 3×3 MoS<sub>2</sub> supercell, and spatial structure of wavefunction norms for the six bands below the Nbm-HOMO. Figure S11: AFM and Raman spectra of the three-layer Nbm-MoS<sub>2</sub> flake.

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### Author Contributions

#J.M. and L.W. contributed equally to this work. Y.Z. and P. S. conceived the experiment. J.M. performed the AFM study, spectroscopic characterization and carried out the device fabrication and characterization with the help of Z. B., Q. Z., T. Z., X. P., J. H., X. Y., B. Y., and X. Z.. L.W. performed the DFT calculation under the supervision

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of J. Q and W. J., J. M. and Y.Z. co-wrote the paper. All authors discussed the results and contributed to the interpretation of data as well as to editing the manuscript.

## **Notes**

The authors declare no competing interests.

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